SUBSTRATE PROCESSING APPARATUS

ABSTRACT

There is provided a substrate processing apparatus for processing a substrate, the substrate processing apparatus including: a first processing module group including one or more first processing modules; a first transfer module connected to the first processing module; a second processing module group including one or more second processing modules; and a second transfer module connected to the second processing module. The first transfer module is disposed above the second processing module, and the second transfer module is disposed below the first processing module.

Figure 2